



FIG. 4

100 - Provide a substrate confinement apparatus having at least one substrate retainer.

110 - Position substrate in a substrate confinement apparatus for processing.

120 - Activate an actuator to urge one of the substrate retainers toward the substrate and urge a contact surface of the substrate retainer into contact with the substrate backside.

130 - Couple one of the retainer bodies and the contact surface of the substrate retainer to the substrate backside.

140 - Retract actuator from the flexure and retainer, thereby leaving one of the retainer bodies coupled to the substrate backside and allow substrate and substrate retainer to settle into a neutral state.

150 - Activate global confinement system to maintain the substrate in a substantially planar position.

160 - Process the substrate